



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Jun HATAKEYAMA et al.

Examiner: Rosemary E. Ashton

Serial No.: 09/842,114

Art Unit: 1752

Filed: April 26, 2001

For: POLYMER, CHEMICALLY AMPLIFIED RESIST COMPOSITION AND

PATTERNING PROCESS

0.K.

REPLY UNDER 37 CFR §1.116

TO ENTEV Mail Stop AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

10-2204

Sir:

In response to the Office Action dated July 29, 2004, please amend the application as follows and consider the remarks.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 20 of this paper.